

## INTERNATIONAL SEARCH REPORT

International Application No

PCT/GR/00003

A. CLASSIFICATION OF SUBJECT MATTER  
 IPC 7 B81B3/00 G01K7/02 G01F1/684

According to International Patent Classification (IPC) or to both national classification and IPC

## B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)

IPC 7 B81B G01K G01F

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practical, search terms used)

EPO-Internal, WPI Data, PAJ, INSPEC, COMPENDEX

## C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
X	TJERKSTRA R W ET AL: "Multi-walled microchannels: free-standing porous silicon membranes for use in mu TAS" JOURNAL OF MICROELECTROMECHANICAL SYSTEMS, DEC. 2000, IEEE, USA, vol. 9, no. 4, pages 495-501, XP002212547 ISSN: 1057-7157 cited in the application figures 3,4 paragraph 'IIIA!	1
Y		2,3,5,7
A		4,6,8-10
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☒ Further documents are listed in the continuation of box C.

☒ Patent family members are listed in annex.

## \* Special categories of cited documents:

- \*A\* document defining the general state of the art which is not considered to be of particular relevance
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- \*O\* document referring to an oral disclosure, use, exhibition or other means
- \*P\* document published prior to the international filing date but later than the priority date claimed

- \*T\* later document published after the international filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention
- \*X\* document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone
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Date of the actual completion of the international search

11 April 2003

Date of mailing of the international search report

23/04/2003

Name and mailing address of the ISA

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## INTERNATIONAL SEARCH REPORT

International Application No

PCT/03/00003

## C.(Continuation) DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
Y	KALTSAS G ET AL: "Novel C-MOS compatible monolithic silicon gas flow sensor with porous silicon thermal isolation" SENSORS AND ACTUATORS A, ELSEVIER SEQUOIA S.A., LAUSANNE, CH, vol. 76, no. 1-3, 30 August 1999 (1999-08-30), pages 133-138, XP004184426 ISSN: 0924-4247 cited in the application figures 1,2 paragraphs '0002!', '0003!	2,3,5,7
A		1,4,6, 8-10
X	LAMMEL G ET AL: "Free-standing, mobile 3D porous silicon microstructures" SENSORS AND ACTUATORS A, ELSEVIER SEQUOIA S.A., LAUSANNE, CH, vol. 85, no. 1-3, 25 August 2000 (2000-08-25), pages 356-360, XP004214496 ISSN: 0924-4247 cited in the application figures 2-4 paragraphs '02.3!', '02.4!	1
A		2-10
X	WO 98 50763 A (NASSIOPOULOU ANDROULA G ;NCSR DEMOKRITOS (GR); KALTSAS GRIGORIS (G) 12 November 1998 (1998-11-12) cited in the application figures 1,3 page 2, line 9 -page 3, line 4	4,6,9
A		1-3,5,7, 8,10
X	DATABASE WPI Section EI, Week 200038 Derwent Publications Ltd., London, GB; Class U12, AN 2000-432097 XP002212548 & CN 1 251 945 A (TU X), 3 May 2000 (2000-05-03) abstract	8,10
A P,X	-& US 6 359 276 B1 (TU XIANG ZHENG) 19 March 2002 (2002-03-19) figures 1-12 column 3, line 10 -column 7, line 27	1-7,9 8,10
A		1-7,9
	-/-	

## INTERNATIONAL SEARCH REPORT

International Application No

PCT/93/00003

## C.(Continuation) DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
A	ANGELUCCI R ET AL: "Permeated porous silicon for hydrocarbon sensor fabrication" SENSORS AND ACTUATORS A, ELSEVIER SEQUOIA S.A., LAUSANNE, CH, vol. 74, no. 1-3, 20 April 1999 (1999-04-20), pages 95-99, XP004188065 ISSN: 0924-4247 figure 1 paragraph '0002!	1-10
A	DOBRZANSKI ET AL: "Micromachined silicon thermopile and thermal radiators using porous silicon technology" IEE PROCEEDINGS: OPTOELECTRONICS, INSTITUTION OF ELECTRICAL ENGINEERS, STEVENAGE, GB, vol. 145, no. 5, 16 October 1998 (1998-10-16), pages 307-311, XP006011364 ISSN: 1350-2433 paragraphs '03.2!, '04.2!; figure 2	1-10

# INTERNATIONAL SEARCH REPORT

Information on patent family members

International Application No

PCT/GR 000003

Patent document cited in search report		Publication date		Patent family member(s)	Publication date
WO 9850763	A	12-11-1998	GR WO	1003010 B 9850763 A1	20-11-1998 12-11-1998
CN 1251945	A	03-05-2000	US	6359276 B1	19-03-2002